課題番号	:F-17-UT-0069
利用形態	:機器利用
利用課題名(日本語)	:
Program Title (English)	:Soft X-ray Charged Piezoelectret with Embedded Electrodes
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キーワード/Keyword	:リソグラフィ・露光・描画装置, Flexible Piezoelectret, Soft X-ray charging

## <u>1. 概要(Summary)</u>

A flexible piezoelectret energy harvester with embedded electrodes is proposed. With the aid of soft X-ray charging and high-performance electret CYTOP-M, output power of 2.8  $\mu$ J has been obtained for 0.6 mm displacement in 0.4 s, with the max applied mechanical force as low as 0.9 N and piezoelectric coefficient d<sub>33</sub> as high as 16000 pC/N.

### <u>2. 実験(Experimental)</u>

## 【利用した主な装置】

高速大面積電子線描画装置,マスク・ウエーハ自動現 像装置群,ブレードダイサー

### 【実験方法】

20  $\mu$ m-thick parylene-C layers with a Cr/Au/Cr electrode are used as the membrane. 200  $\mu$ m-high SU-8 pillars are patterned on the parylene-C layer by photolithography. After detachment from the wafer, the chips are dip-coated with high-performance electret CYTOP-107M (Asahi Glass), with the coating thickness of 7  $\mu$ m on each surface. Finally, stacked 4-layered structure is formed and charged with soft X-ray charging.

## 3. 結果と考察(Results and Discussion)

As shown in Fig. 1, thin-film electrodes are integrated into the multi-layered structure, so that the bias voltage is directly applied to each layer during the soft X-ray charging. Power generation experiment is made using a setup shown in Fig. 2. The 4-layered structure is poled using soft X-ray charging with bias voltage of 600 V for 30 min. Up to 100 V is obtained for 0.6 mm displacement in 0.4 s, which corresponds to 2.8  $\mu$ J output energy. The effective Young's modulus is as low as 15 kPa, so that the maximum applied force is as low as 0.9 N. This leads to extremely-large d<sub>33</sub> of 16000 pC/N, which is even higher than cellular PDMS.

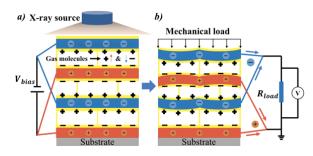


Figure 1. Multi-layered piezoelectret structures with embedded electrodes. a) Charging, b) Operation.

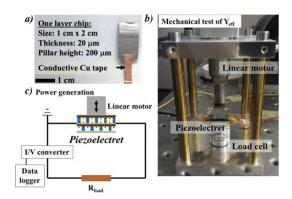


Figure 2. a) Single layer chip dip-coated by CYTOP. b) Measurement of effective Young's modulus using a load cell. c) Power generation experiment.

# <u>4. その他・特記事項(Others)</u>

# なし

#### <u>5. 論文·学会発表(Publication/Presentation)</u>

- J. Lu & Y. Suzuki, 16th Int. Symp. on Electrets (ISE16), Leuven, Belgium, Sept., 2017.
- (2) J. Lu & Y. Suzuki, 31st IEEE Int. Conf. on Micro Electro Mechanical Systems (MEMS2018), Belfast, pp. 646-648 (2018).

# <u>6. 関連特許(Patent)</u>